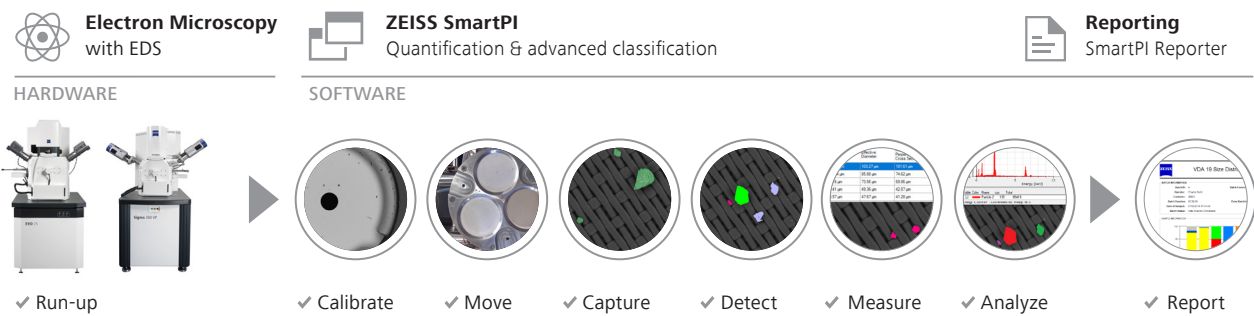


Identify the root cause.
 Make the right decision faster.

ZEISS SmartPI

Technical Cleanliness Solution for Electron Microscopy

ZEISS SmartPI has been designed for repeatable, high-volume analysis of routine samples in a production environment. The ability to identify, analyse and report contamination data, creates a new dimension in process control. Take the next step forward in Technical Cleanliness with ZEISS SmartPI – which now includes the support for Oxford EDS detectors. Benefit from significant improvements in fully automated SEM Particle Analysis and Classification. Let ZEISS SmartPI increase your productivity, increase your quality and reduce your contamination cost.



Your advantages at a glance

- Powerful, versatile, all-in-one particle analysis application for your ZEISS EVO & ZEISS Sigma family.
- A complete turnkey solution, which fully automates repetitive sample analysis and provides non-subjective results, with minimal user interaction.
- Full control of the SEM, advanced image processing, image analysis and elemental analysis (EDS) - all driven from a single application.
- Automatically detects, measures, counts and classifies particles of interest, based on morphology & elemental composition.
- Industry standard reports are automatically generated, like VDA 19.1 & ISO16232.
- Fully integrated & compatible with Bruker & Oxford EDS systems.
- Supports Correlative Automated Particle Analysis with ZEISS Light Microscopes.

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Seeing beyond